

AUTOMATIC ELECTRON BEAM ANALYZER

Patent Number: JP2000268764
Publication date: 2000-09-29
Inventor(s): NIWA NAOMASA; YAMADA TADASHI; YAHAGI EIJI
Applicant(s): SHIMADZU CORP
Requested Patent: JP2000268764
Application Number: JP19990073434 19990318
Priority Number(s):
IPC Classification: H01J37/252; G01N23/225; H01J37/21
EC Classification:
Equivalents:

Abstract

PROBLEM TO BE SOLVED: To automatically analyze an analyzing point by automatically positioning the analyzing point to the beam center without a manual operation.

SOLUTION: This automatic analyzer 1 has a stage 7 for moving a sample against an electron beam 12, and an image processing means 4 which obtains an image data obtained by irradiation of the electron beam 12 in a different visual field magnification and calculates positional data of a branch point in the different visual field magnification. By automatically recognizing the branch point under the analyzing condition for the sample by electron beam analysis, automatic positioning of analyzing point to the beam center can be performed without a normal operation, thereby automatic analysis is performed.

Data supplied from the **esp@cenet** database - I2
